## **Gas Purifier and Thermal Conductivity Detector**



### **Miniature Gas Purifiers**

The Valco Miniature Helium Purifier (HPM) and Miniature Nitrogen Purifier (NPM) are designed to be installed in a gas chromatograph's flow path immediately upstream of the injector.

The HPM/NPM will remove any contaminants introduced by flow controllers, elastomeric tube seals, pressure regulators, crude traps, or other system components that are not completely clean and leak-tight.

#### Mini helium and nitrogen purifiers

Includes universal power supply.

	Helium purifier	Nitrogen purifier
Description	Prod No	Prod No
110 VAC	HPM	NPM
230 VAC	HPM-220	NPM-220



# **Microvolume Thermal Conductivity Detector**

Our dual filament TCD is a stand-alone unit consisting of the detector housing and a controller with electrometer and temperature controls. The detector cell includes two separate nickel/iron filaments, capable of independent or referenced (differential) operation. Cell volume and geometry are optimized for capillary chromatography and enhanced sensitivity at low flow

rates. (Recommended total flow rate: 2-10 mL/min.) Thermal stability is maintained to ±0.02°C, resulting in a stable, noise-free signal. A single 0-1 millivolt attenuated output for a strip chart recorder is provided through the signal cable at the rear of the controller, with 0-1 volt and 0-10 volt unattenuated signals available through the remote signal cable.

## **TCD** Thermal conductivity detectors

	110 VAC	230 VAC
Description	Prod No	Prod No
Entire unit (cell and electronics)	TCD2-NIFE	TCD2-NIFE-220
Cell/oven assembly only Dual filament	TCD2-NIFED	TCD2-NIFED-220
TCD controller only	TCD2-C	TCD2-C-220